

# Review\* of Metallic Resists for EUV

Robert Brainard<sup>a</sup> and Lisa Brainard<sup>b</sup>

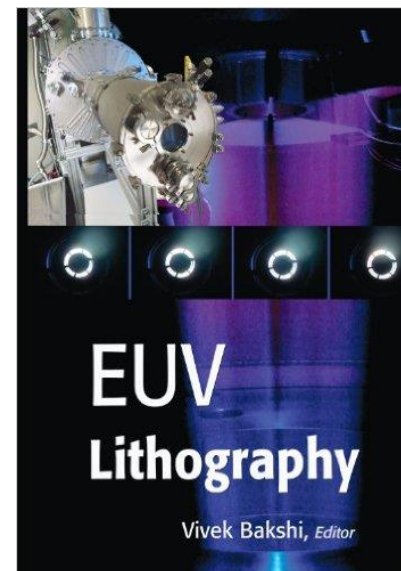
a. Colleges of Nanoscale Science and Engineering; SUNY Polytechnic Institute

b. Sage College

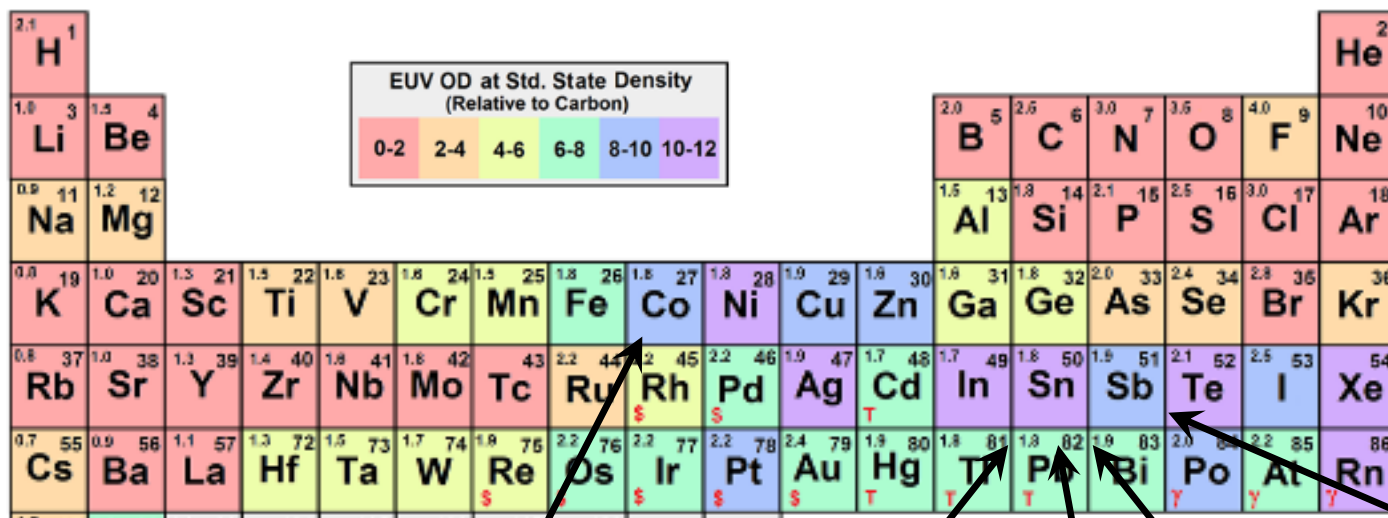
- I. Metal-Oxo Films (OSU/Inpria)
- II. HfOx and ZrOx Nanoparticles (Cornell)
- III. Molecular Organometallic Resists for EUV (MORE)  
(SUNY Poly and New Paltz)
  - A. Tin Oxo Clusters (Cardineau)
  - B. Tin Carboxylates (Del Re)
  - C. Transition Metal Oxalates (Freedman)
  - D. Positive-Tone Palladium (Sortland)
  - E. High-Speed Main-Group Olefins (Passarelli)

## IV. Acknowledgements

**\*For 2<sup>nd</sup> Edition:**

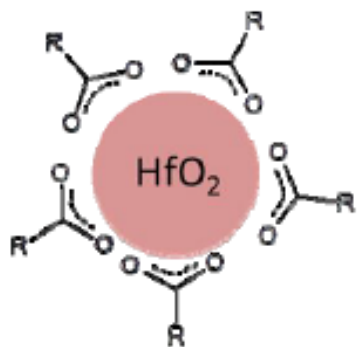


# Optical Density Map of the Elements

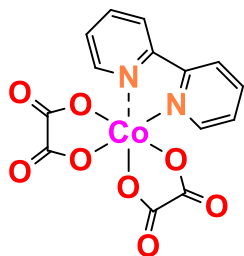


Inpria  
HafSOx

Super-Fast  
Nanoparticles

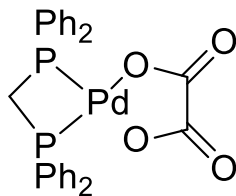


Negative Tone



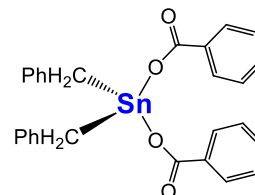
Cardineau & Brainard *MicElec* 127 (2014) 44

Positive Tone

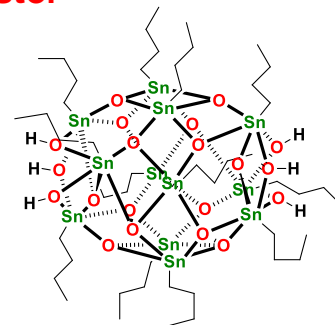


Inpria  
SnOx

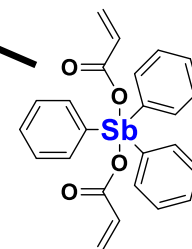
Super-Low LER



Tin-Oxo  
Cluster

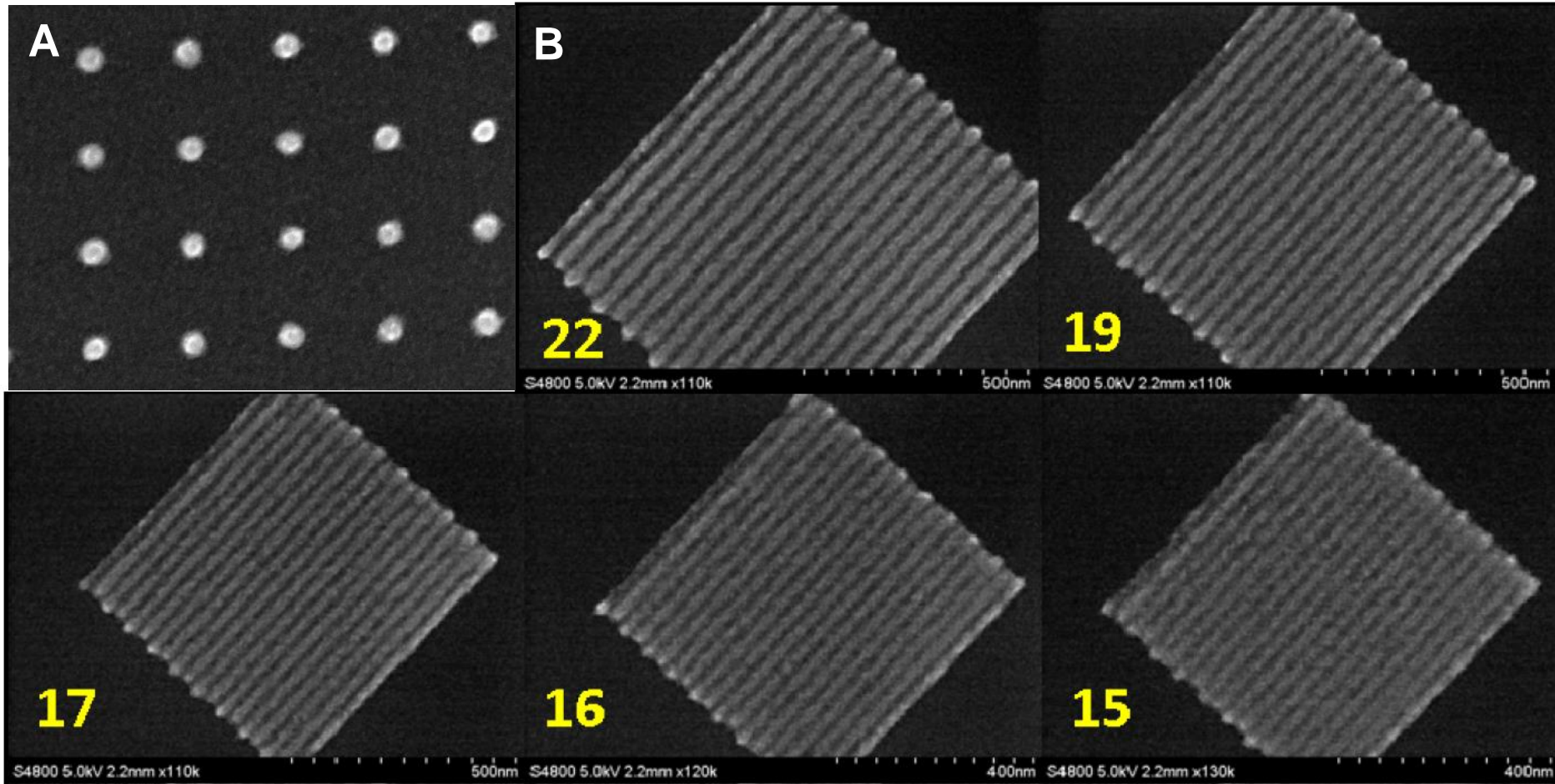


Super-Fast



# I. Metal-Oxo Films (OSU/Inpria)

First Publication of EUV Results. BMET SPIE 2010

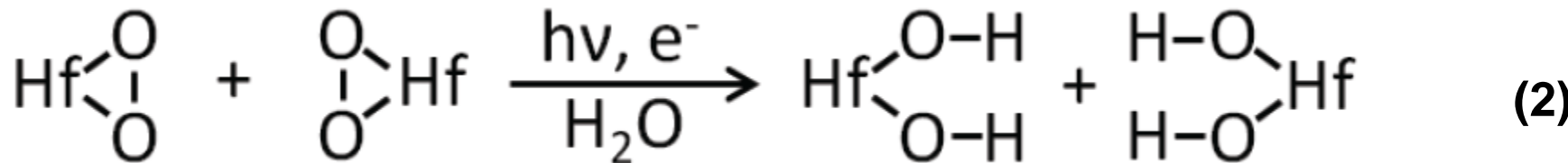
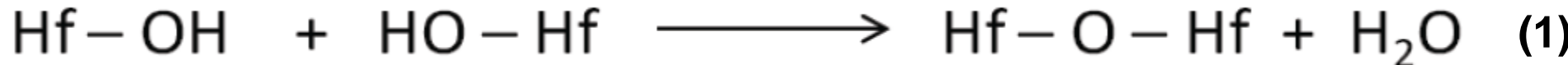


# I. Metal-Oxo Films (OSU/Inpria)

## Published Photoreactivity

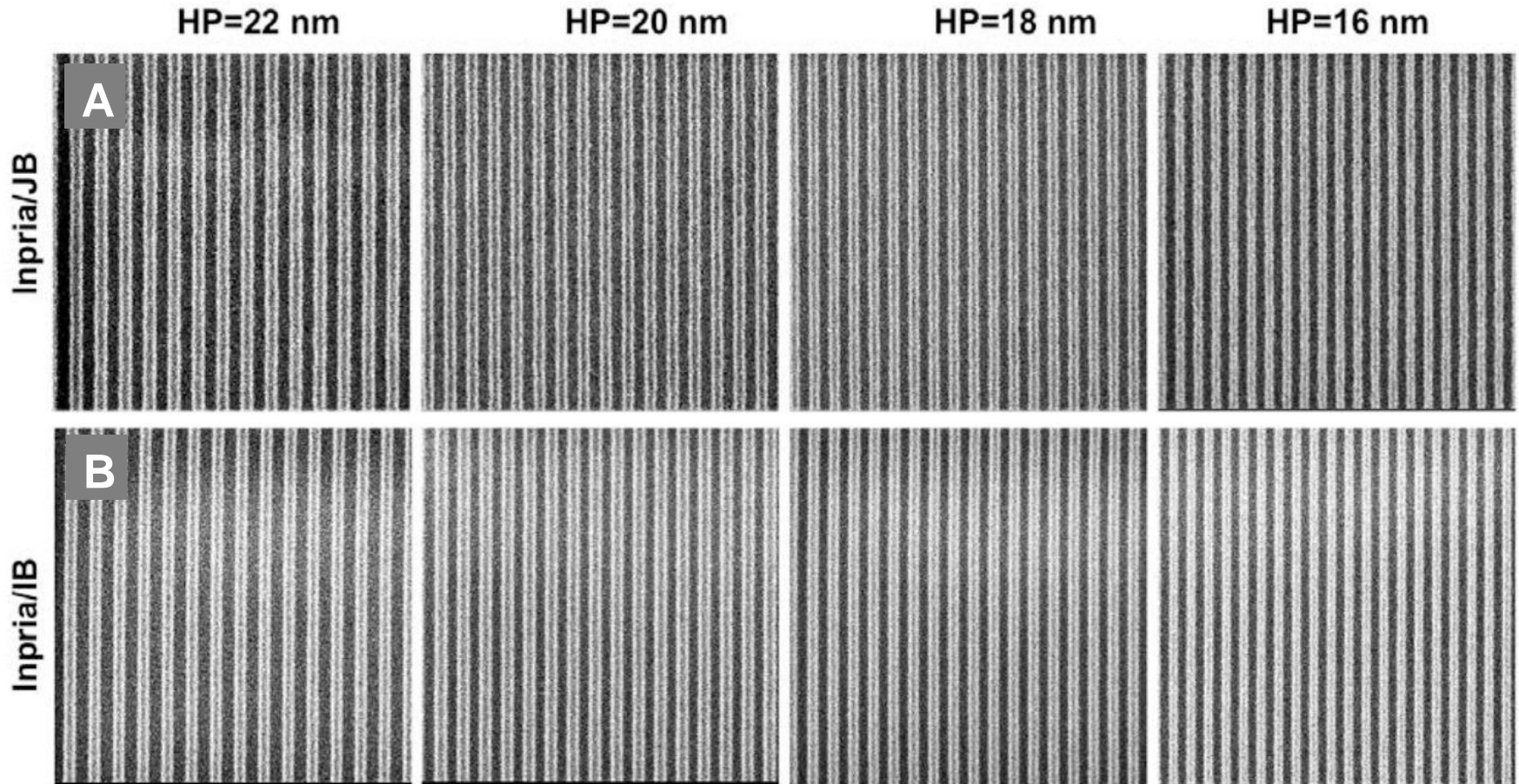
The key to the photoreactivity of the  $\text{HfSO}_x$  resists appears to be controlling the dehydration reaction (eq 1) which crosslinks and thereby reduces the solubility of these metal oxo-films. Dehydration is prevented by binding peroxide to Hf. Fortunately, the metal peroxide decomposition can be induced by high-energy light or electrons (eq 2) thereby creating metal hydroxides that can condense and become insoluble.

In brief, the metal peroxides allow the resists to dissolve in the unexposed regions and upon photolysis the metal peroxides become metal hydroxides and condense to become insoluble features of the negative-tone resists.



# I. Metal-Oxo Films (OSU/Inpria)

## Imaging at PSI (2014)

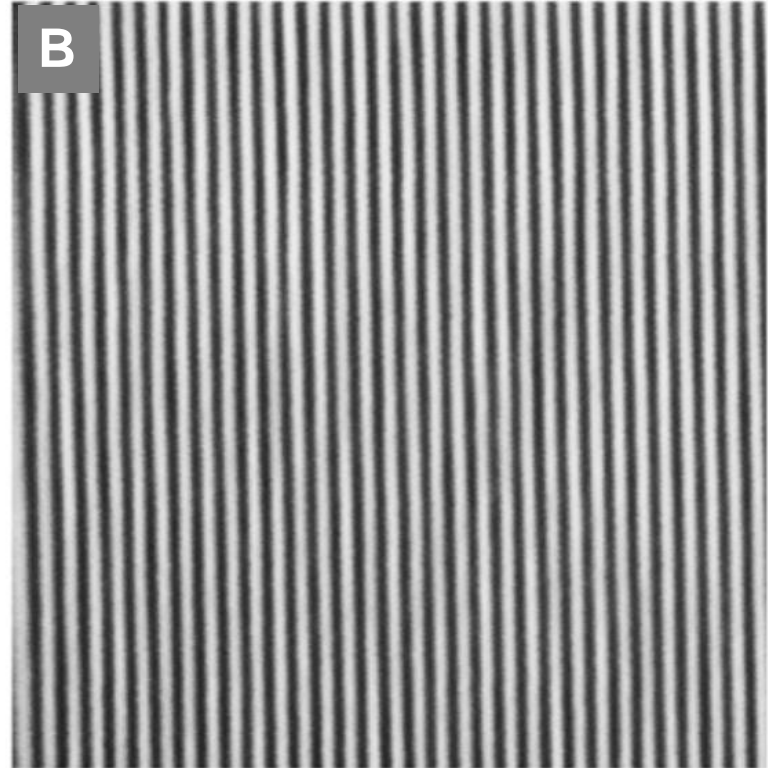
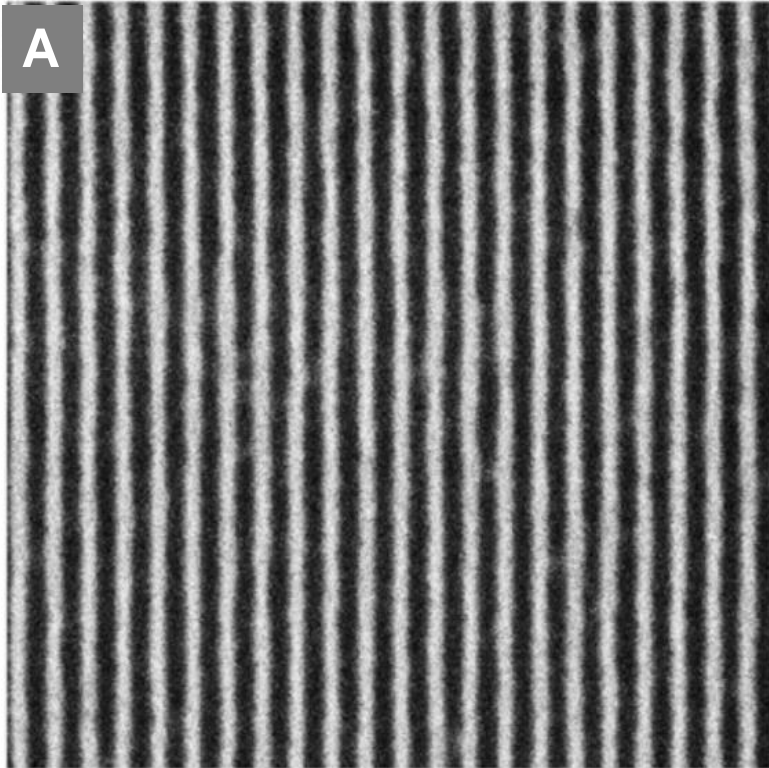


# I. Metal-Oxo Films (OSU/Inpria)

## Imaging at PSI (2014)

HP=12 nm

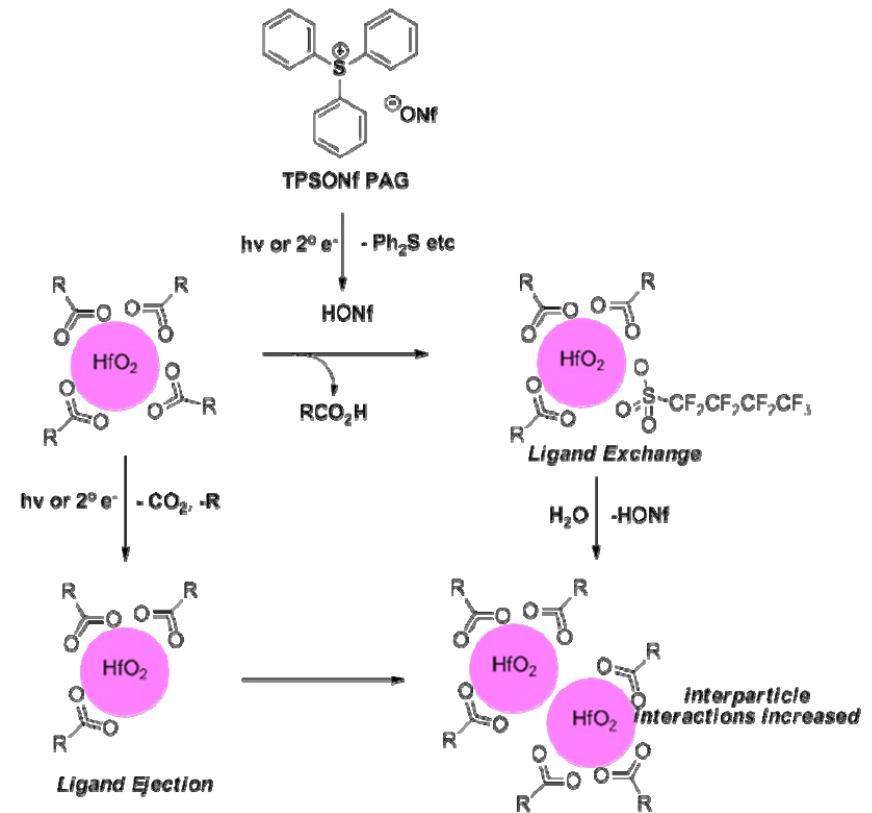
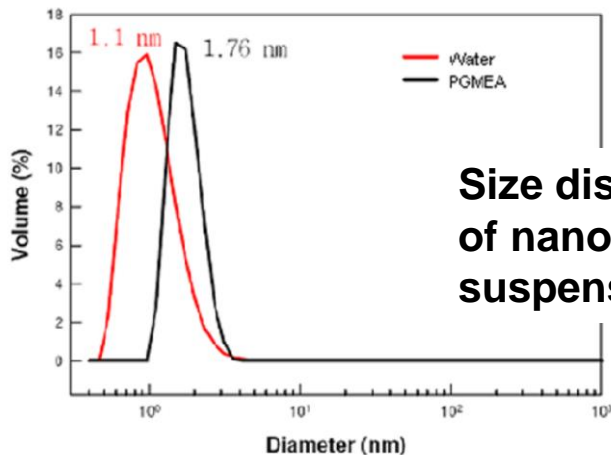
HP=8 nm



# II. HfOx and ZrOx Nanoparticles (Cornell)

Many versions of these resists were prepared using methacrylate as a ligand and formulated with either photoacid generators or free-radical initiators, suggesting that the negative-tone imaging mechanisms might involve free-radical crosslinking.

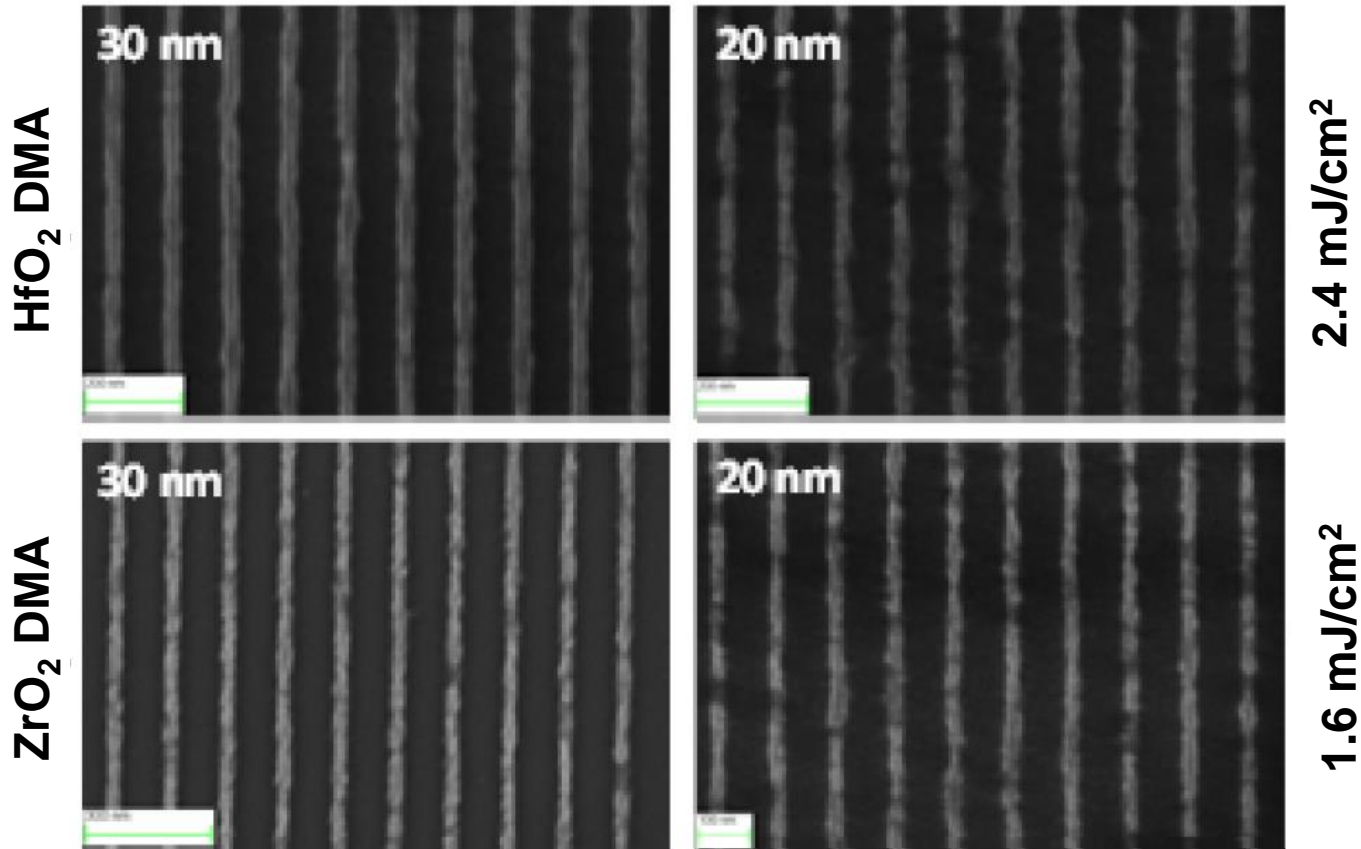
However, careful studies revealed that the negative-tone solubility switches do not involve free-radical crosslinking, but instead involves a ligand exchange mechanism that can proceed without PAGs or with the assistance of PAGs.



## II. HfO<sub>x</sub> and ZrO<sub>x</sub> Nanoparticles (Cornell)

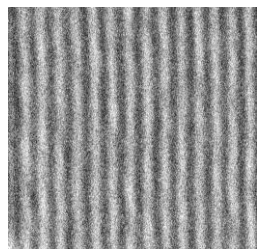
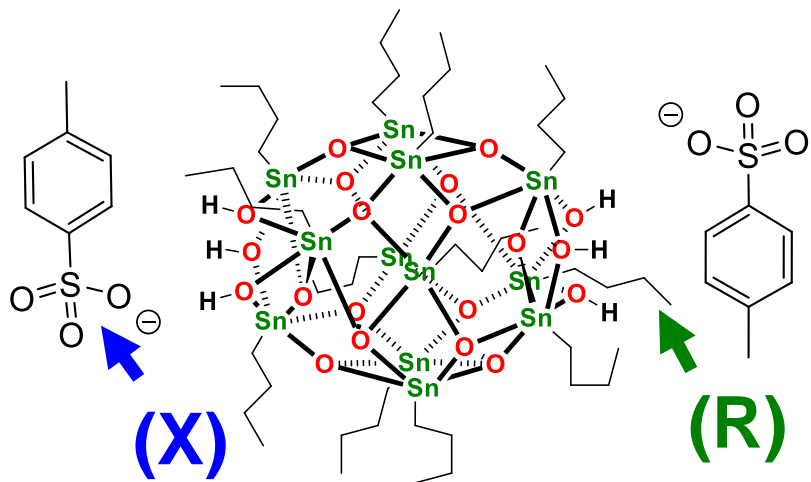
These nanoparticle resists are capable of good EUV patterning capability at extremely fast photospeeds. 20 and 30 nm isolated lines were printed using doses of 2.4 and 1.6 mJ/cm<sup>2</sup>.

Although the LER values of these resists are modest (5-7 nm), the LER is not too poor considering that the resists are extremely sensitive and are composed of nanoparticles that are 1-2 nm in diameter.



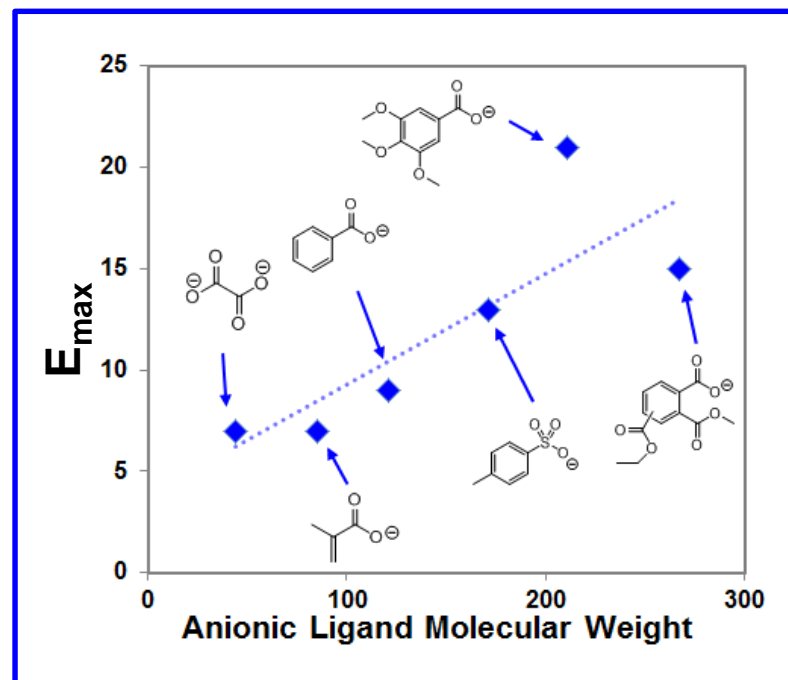


# III. MORE: A. Tin Oxo Clusters (Cardineau)



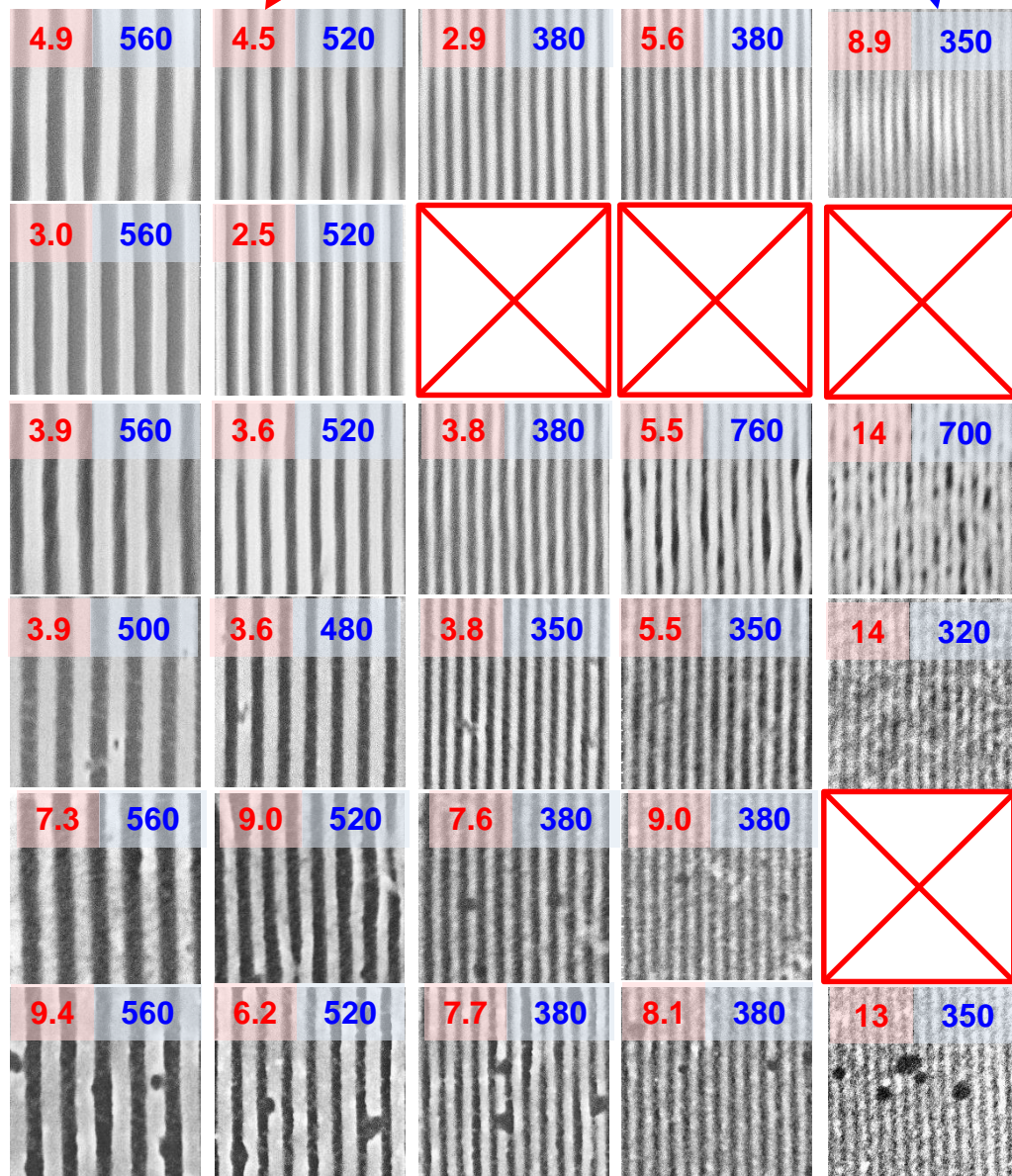
Dose: 350 mJ/cm<sup>2</sup>

Resolution: 18 nm



The resist sensitivity shows good correlation with anion size.

LER (nm)

Dose (mJ/cm<sup>2</sup>)

50

35

25

22

18

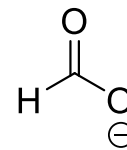
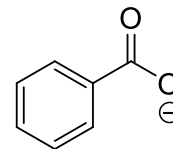
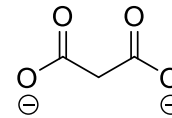
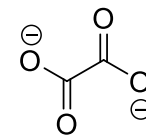
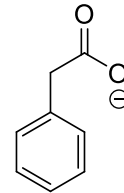
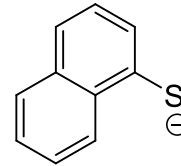
EUV Symposium 6/16  
Brainard and Brainard

h/p CD (nm)

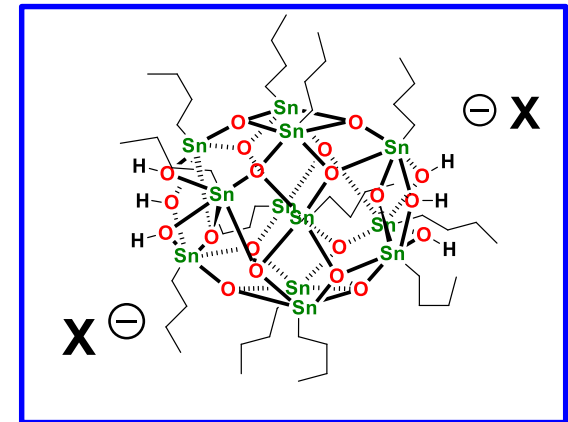
Cardineau &amp; Brainard MicElec 127 (2014) 44

10

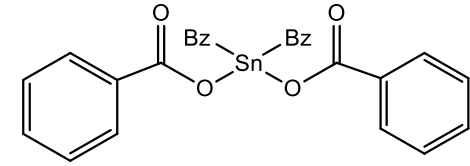
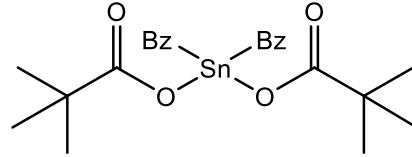
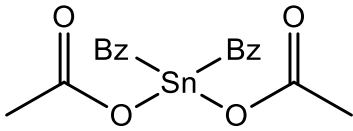
X



# Resolution Capabilities for Various Anions.



# II. MORE: B. Low LER Tin Resists (Del Re)



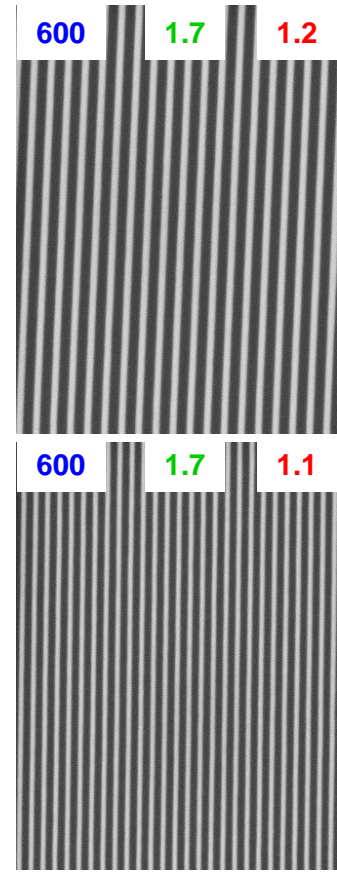
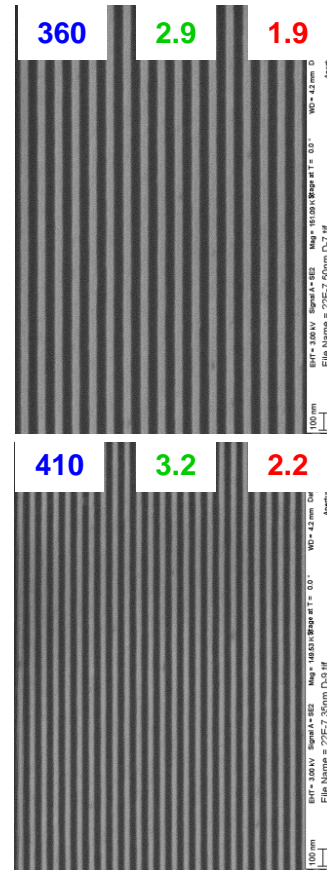
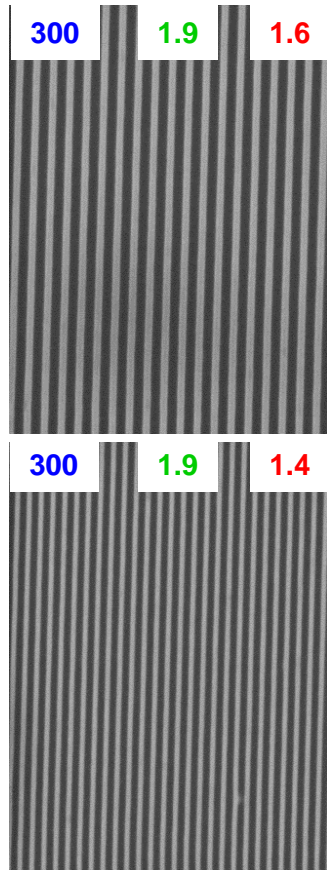
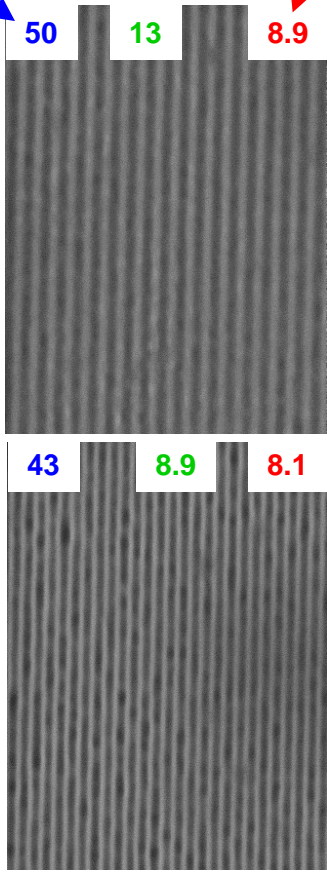
Dose (mJ/cm<sup>2</sup>)

LER (nm)

LWR (nm)

50 nm

35 nm

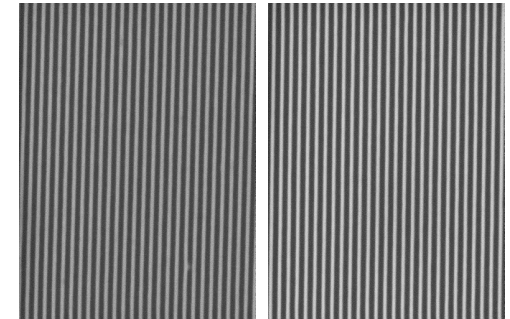
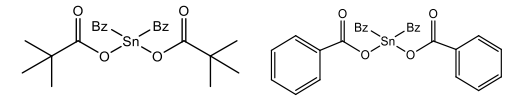
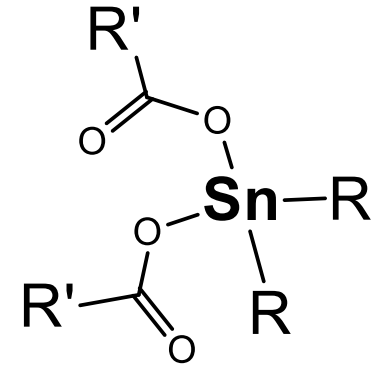
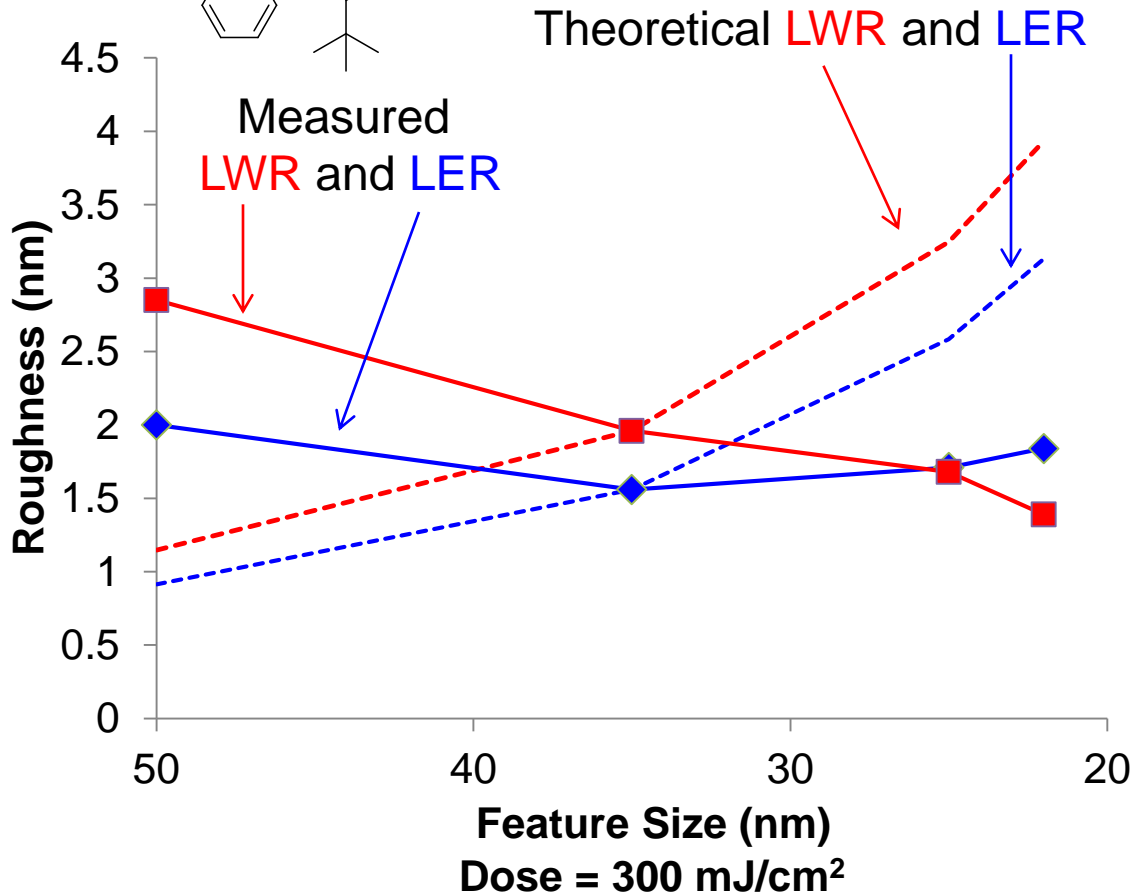
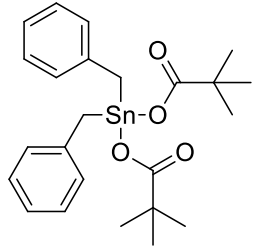


2000 RPM

4000 RPM

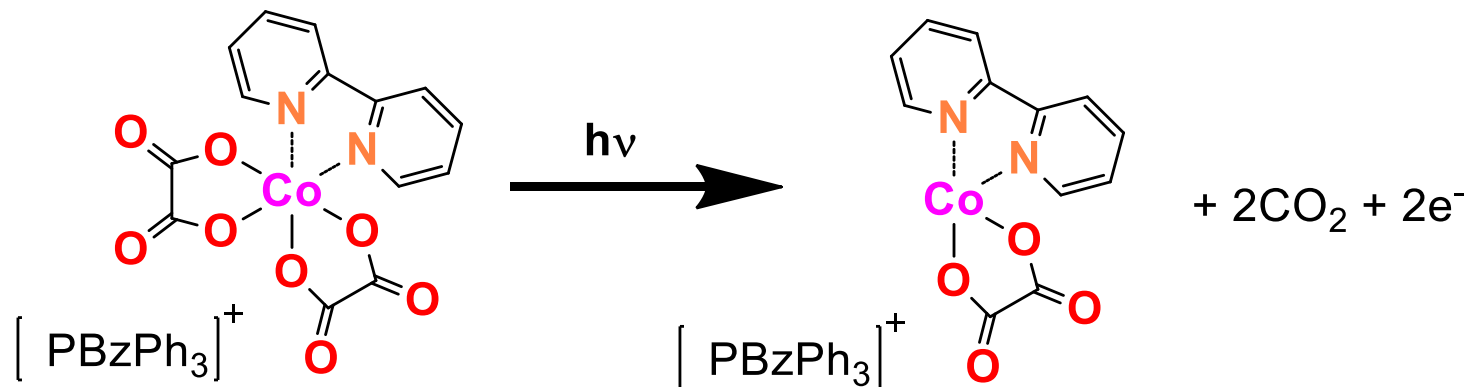
# II. MORE: B. Low LER Tin Resists (Del Re)

## LER Does Not Follow Z Parameter

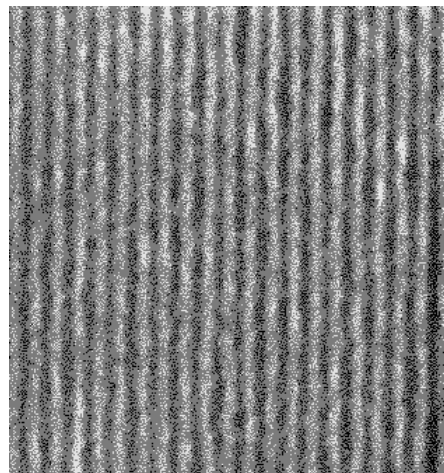


CD: 35 nm	35 nm
LER: 1.4 nm	1.1 nm
LWR: 1.9 nm	1.7 nm

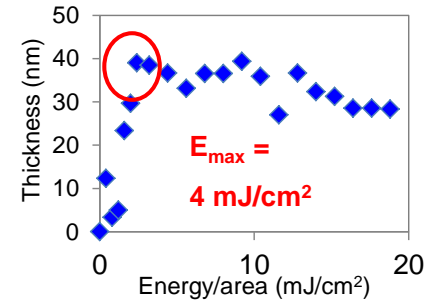
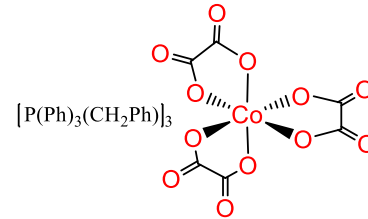
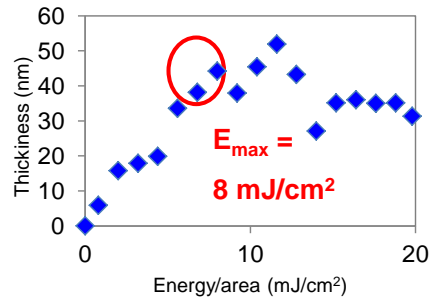
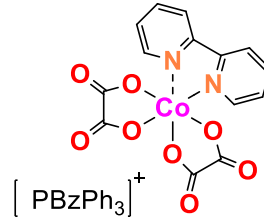
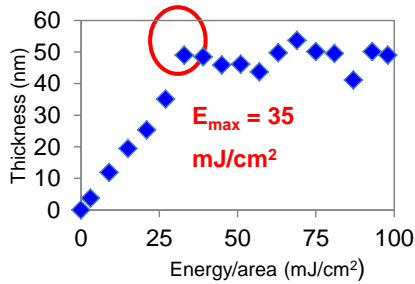
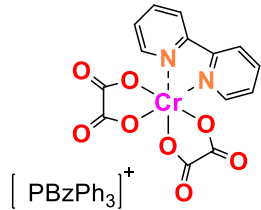
# III. MORE: C. Transition Metal Oxalates (Freedman)



18 nm  
30 mJ/cm<sup>2</sup>



# III. MORE: C. Transition Metal Oxalates (Freedman)



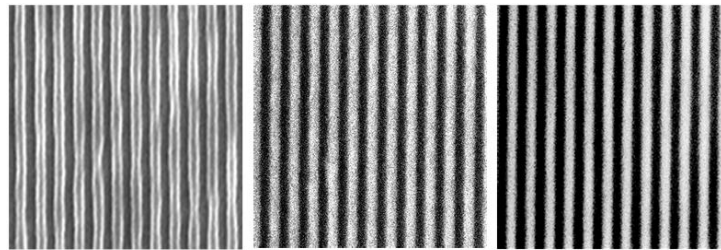
Central  
Metal (M):

Cr

Fe

Co

35 nm h/p  
lines:

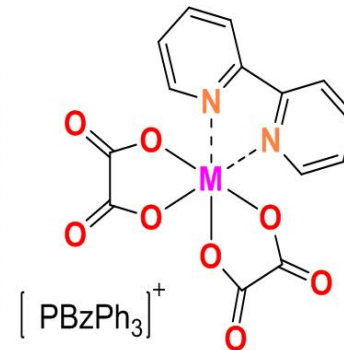


$E_{\text{size}}$   
(mJ/cm<sup>2</sup>):

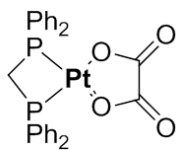
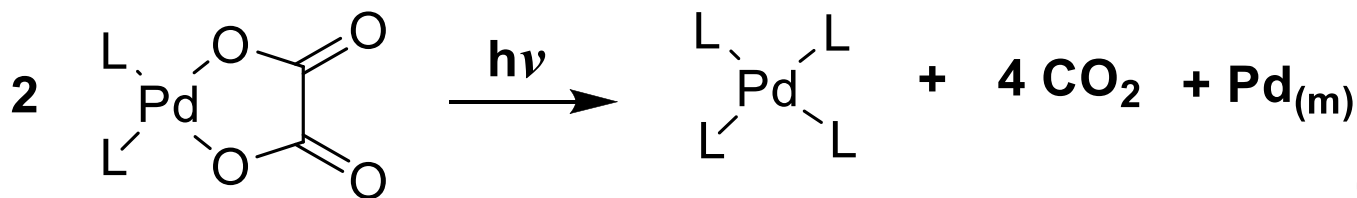
70

48

27

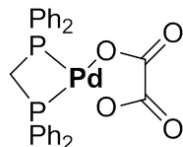


# III. MORE: D. Positive-Tone Palladium Resists (Sortland)



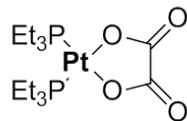
21

247 mJ/cm<sup>2</sup>



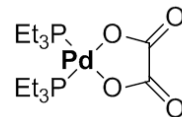
23

54 mJ/cm<sup>2</sup>



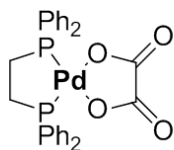
24

157 mJ/cm<sup>2</sup>



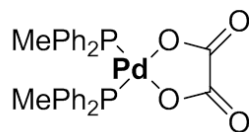
25

110 mJ/cm<sup>2</sup>



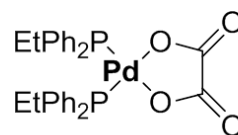
22

110 mJ/cm<sup>2</sup>



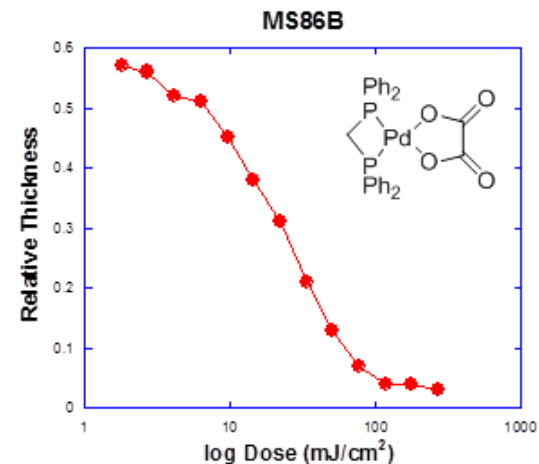
26

35 mJ/cm<sup>2</sup>



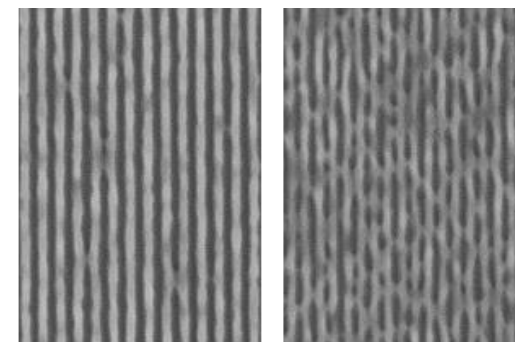
27

71 mJ/cm<sup>2</sup>



30 nm

22 nm

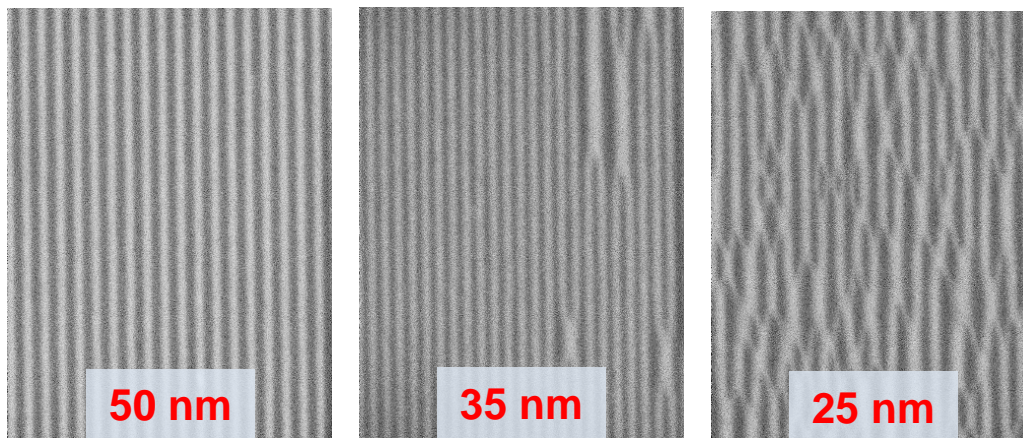
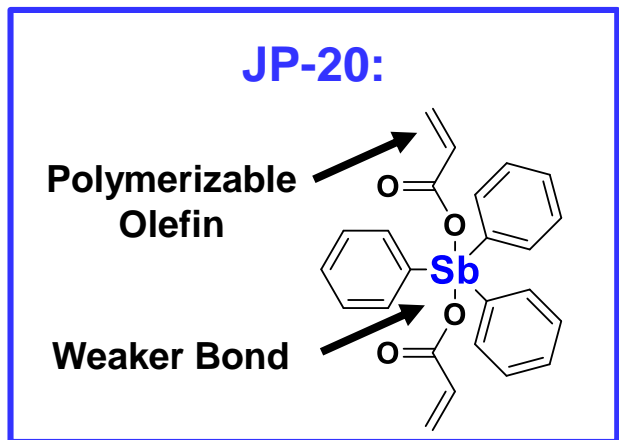


$E_{\text{size}} = 50 \text{ mJ/cm}^2$

# III. MORE: E. High-Speed Main-Group Olefins (Passarelli)

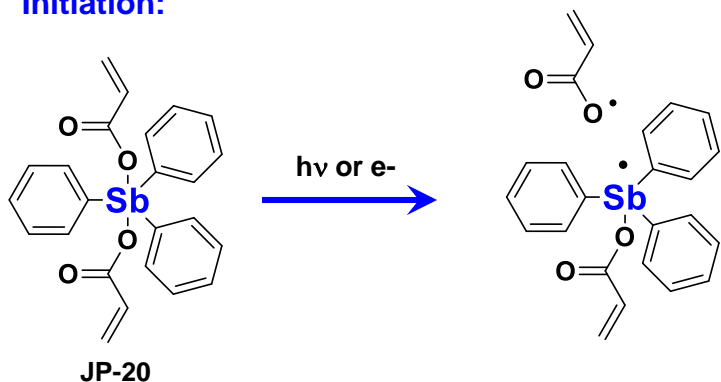
Excellent sensitivity at modest resolution.

Dose = 5.6 mJ/cm<sup>2</sup>

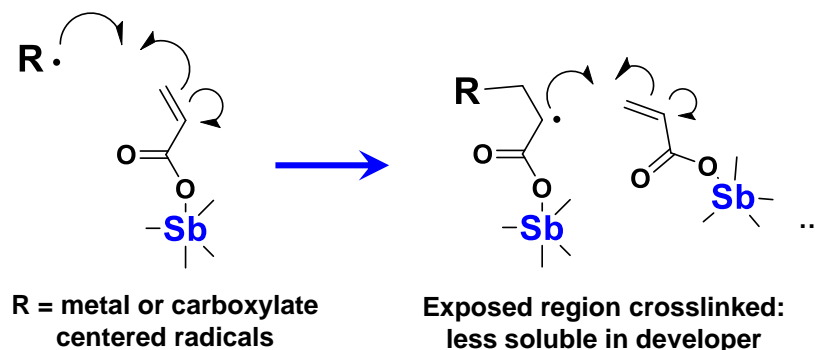


Proposed mechanism is based on photo-initiated free radical polymerization.

Initiation:

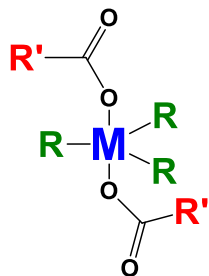
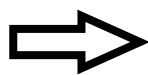
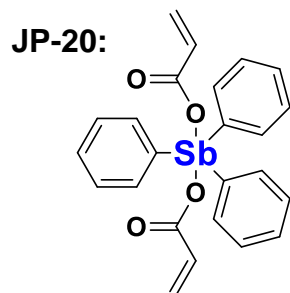


Propagation:





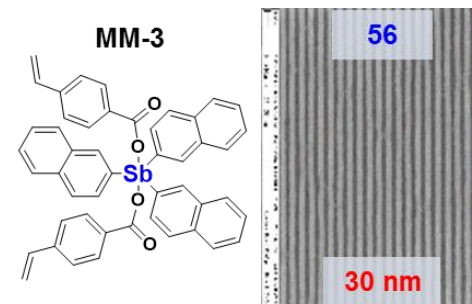
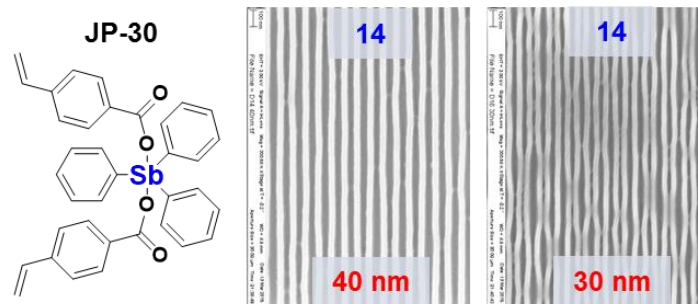
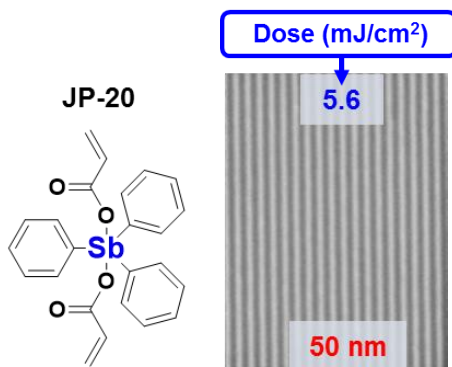
# III. MORE: E. High-Speed Main-Group Olefins (Passarelli)



**M** = Sb, Bi, Sn or Te

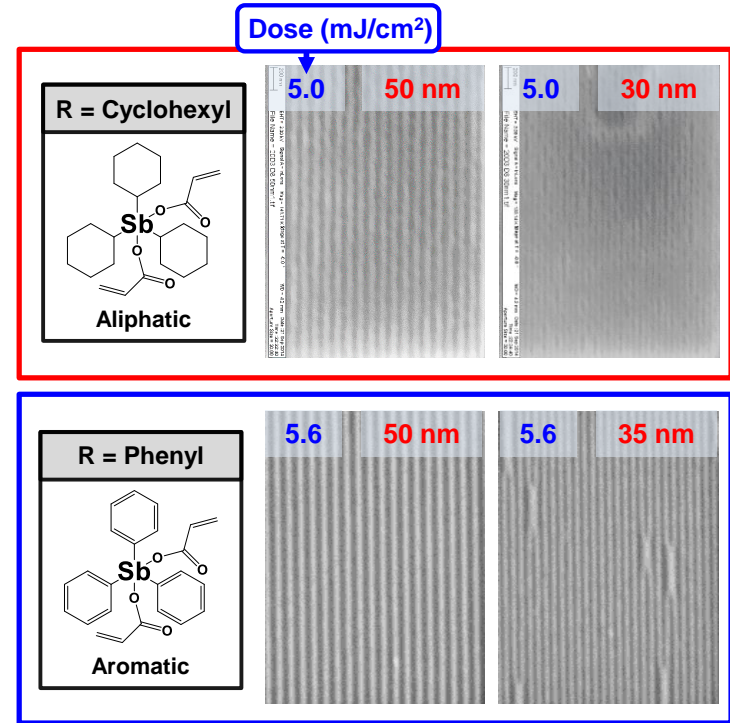
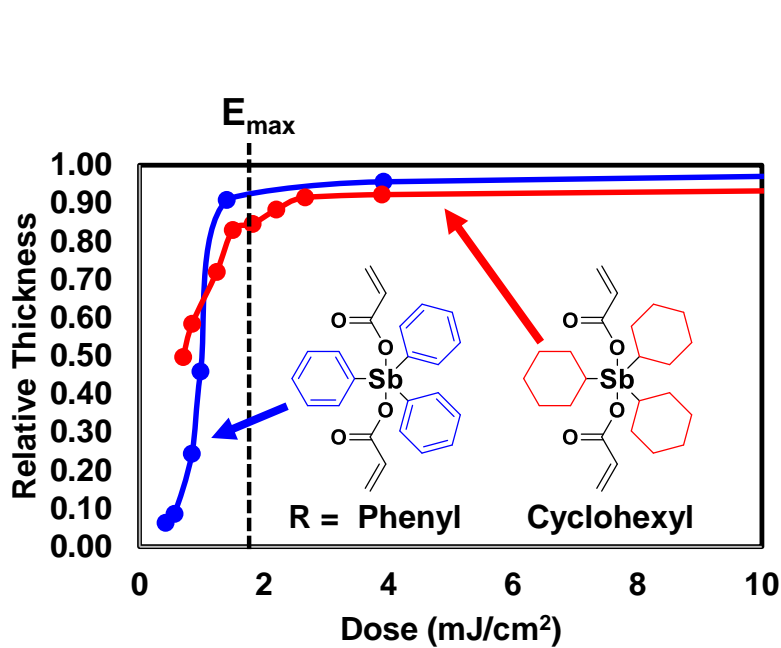
**R** = Aliphatic or Aromatic Sb - C Group

**O<sub>2</sub>CR'** = Carboxylate Group



### III. MORE: E. High-Speed Main-Group Olefins (Passarelli)

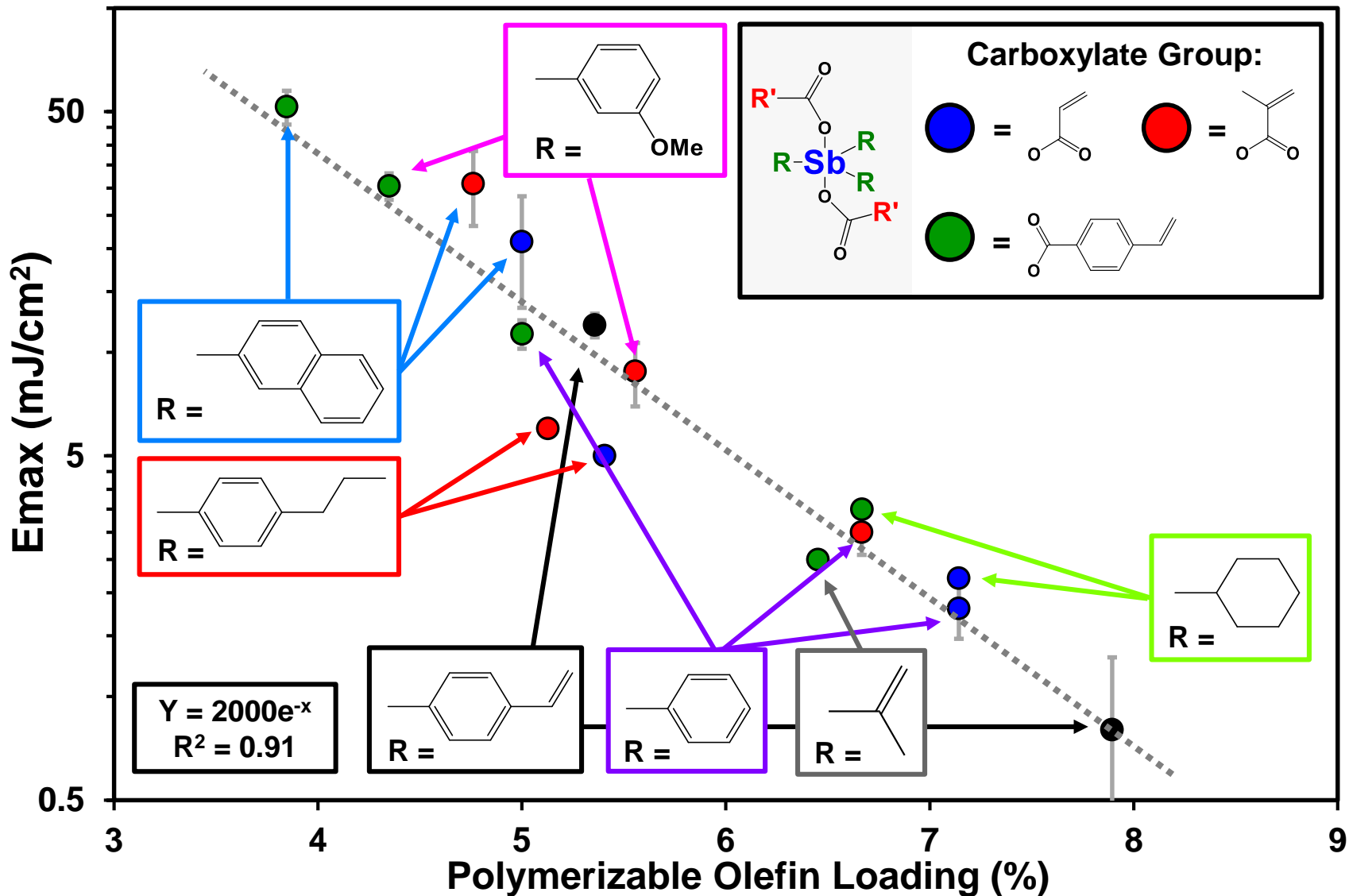
Unexpected Result: Changing Sb-R bond did not dramatically affect sensitivity.



**Sensitivity Hypothesis:** The ratio of polymerizable olefins to space filling R groups is the largest contributor to sensitivity characteristics of antimony acrylate resists.

$$POL = \frac{\# \text{ of Polymerizable Olefins}}{\# \text{ of Atoms (Excluding Hydrogen)}} \times 100\%$$

### III. MORE: E. High-Speed Main-Group Olefins (Passarelli)



# Acknowledgements

## Project Funding By:



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James Blackwell



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Chandra Sarma

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Miriam Sortland  
Michael Murphy  
Jodi Hotalen  
Levi Dousharm  
Brian Cardineau  
Daniel A. Freedman

## PSI:

Michaela  
Vockenhuber  
Yasin Ekinci

## BMET:

Chris Anderson